

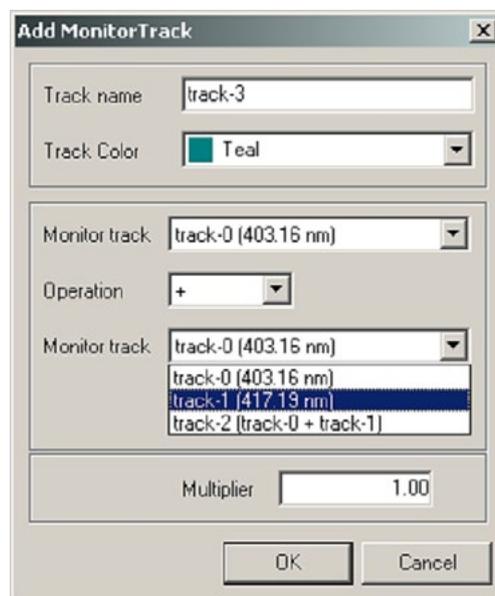
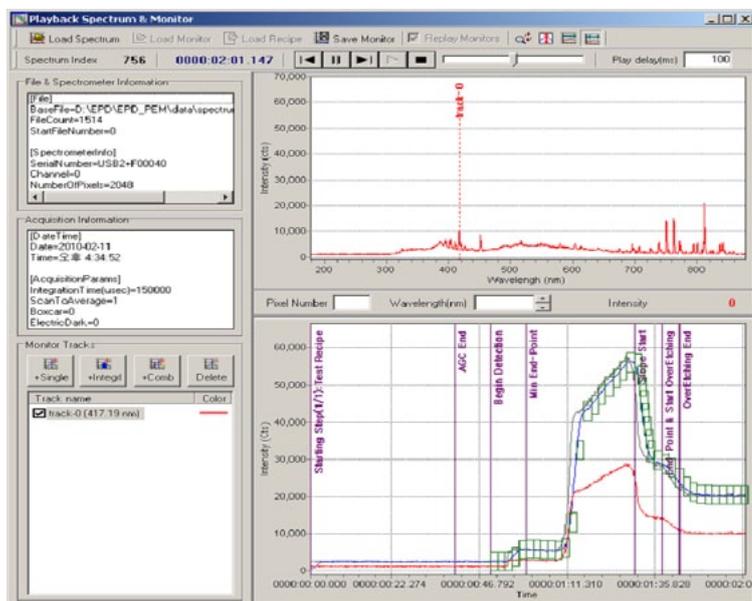
OES/EPD/PEM System EP-202J



Developed by Wonwoo Systems Co., Ltd., EP-202J provides end-point detection (EPD) such as etching and deposition by monitoring and analyzing plasma gas spectroscopy in real time during production processes such as semiconductors, LCDs, and LEDs using Plasma.

- Select a suitable spectrometer depending on the spectral properties of the material (wavelength range, spectral intensity, pixelation)
- Up to 8 analysis channels can be scaled per system
- USB 2.0 interface for communication with monitoring PCs
- Remote remote control over Ethernet network
- Peripheral controller and digital and analog communication input/output capabilities
- Optimal detection conditions using EP software EPD parameter data contained in the system

EP Software



- Display of radio field spectra (OES)
- Selection and combination of monitored wavelengths

- Recipe Support
- Spectrum Reprocessing function (Reanalysis of previously collected spectral data)

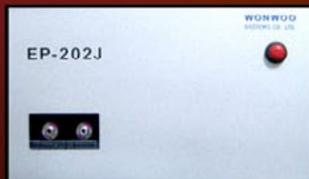
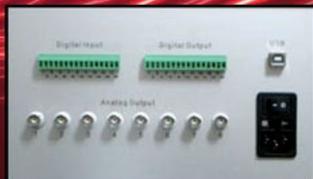


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OES/EPD/PEM System

EP-202J



Specifications

Detector/ Optical	
Detector Type	Sony ILX511B linear silicon CCD array
Spectral Range	200-1100 nm
Optical Resolution	~0.3-10nm (FWHM)
CCD Pixels	2048
Sensitivity	400nm: 75 photons/count 600nm: 41 photons/count
Integration Time	1ms - 65sec
Dynamic range	1300:1
S:N ratio	250:1
EPD/PEM Module	
Channels	1~8 channel
Communication	USB 2.0, Ethernet (IEEE 802.3-compliant 10/100)
TTL In	8/16-channel (0/5V)
TTL Out	8/16-channel (0/5V)
Analog Out	8-channel (0~10V)
Power	110/220VAC, 50/60Hz
Dimensions (mm)	250×300×145
Weight	< 7kg
Software	
Control Software	EPSoft
Functions	OES, EPD, PEM, Data storage & Reprocessing
Software for Identify Elements & Compounds	SPECLINE-U